

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
)	
Babak Heidari et al.)	Group Art Unit: 2833
)	
Application No.: 10/581,497)	Examiner: To be Assigned
)	
Filed: June 2, 2006)	
)	
For: Device and Method for Large Area)	Confirmation No.: 3831
Lithography)	

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT


Enclosed for the consideration of the Examiner in connection with the prosecution of this application is a copy of each of the four documents listed on the attached Form PTO/SB/08 that were cited in the corresponding Japanese patent application.

If there is any fee due in connection with the filing of this Statement, please charge such fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: October 9, 2008

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